

Sheet 1 of 1

**LIST OF ART CITED BY APPLICANT**

(Use several sheets if necessary)

Atty Docket No. <b>99-056</b>	Serial No. <b>09/641,155</b>
Applicant <b>Spencer Wayne Bruce et al.</b>	
Filing Date <b>August 17, 2000</b>	Group <b>1746</b>

**U.S. Patent Documents**

EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	Class/Subclass	FILING DATE IF APPROPRIATE
<i>PS</i>	AA	5,728,272	03/17/98	Hammon et al.	203/8	
	AB					
	AC					
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	AG					
	AH					
	AI					
	AJ					
	AK					

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**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	Class/Subclass	Translation Yes/No
<i>PS</i>	AL	0 248 681 B1	12/16/92	EP		
	AM					
	AN					
	AO					
	AP					
	AR					
	AS					
	AT					

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**OTHER ART (Including Author, Title, Date, Pertinent Patents, etc.)**

<i>PS</i>	AU	CAPLUS 1974:464592, "Removal of Polymer Deposit From Equipment", Nishikawa, Tokutomi; Masuda, Toshihiko, Jan. 25, 1974
	AV	
	AW	

Examiner

Date Considered

\*EXAMINER: Initial reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not conformance and not considered. Include copy of this form with next communication to applicant.

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Applicant

Spencer W. Bruce et al

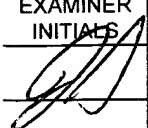
Filing Date

August 17, 2000

Group

1746


**U.S. Patent Documents**

EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	Class/Subclass	FILING DATE IF APPROPRIATE
	AA	5,782,989	07/21/98	Rueter	134/22.19	
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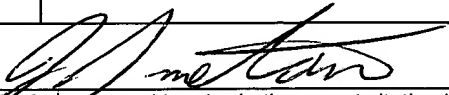
**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	Class/Subclass	Translation Yes/No
	AL	DE 33 25 166 A1	1/24/95	DE		Yes
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	AN					
	AO					
	AP					
	AR					
	AS					
	AT					

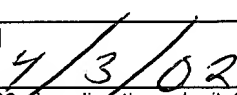
**OTHER ART (Including Author, Title, Date, Pertinent Patents, etc.)**

	AU	
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